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OKW
PATENT
10/03/02

Customer No. 22,852
Attorney Docket No. 04329.2622

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Gaku MINAMIHABA, et al.

Serial No.: 09/932,943

Filed: August 21, 2001

For: SLURRY FOR CHEMICAL
MECHANICAL POLISHING AND
METHOD OF MANUFACTURING
SEMICONDUCTOR DEVICE

)
)
) Group Art Unit: 2823

)
) Examiner: Lee, Hsien Ming

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Assistant Commissioner for Patents
Washington, DC 20231

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In the Restriction Requirement dated September 11, 2002, with a period for response extending through October 11, 2002, the Examiner required restriction under 35 U.S.C. § 121 between Group I (claims 1 – 17) and Group II (claims 18 – 25). Applicants provisionally elect to prosecute Group II, claims 18 – 25, as thus characterized by the Examiner.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By:

Richard V. Burgujian
for Richard V. Burgujian
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Dated: October 3, 2002

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